

Title (en)
GAS INLET FOR AN ION SOURCE

Title (de)
GASEINLASS FÜR EINE IONENQUELLE

Title (fr)
DISPOSITIF D'ADMISSION DE GAZ POUR SOURCE D'IONS

Publication
EP 1082749 A2 20010314 (DE)

Application
EP 99925006 A 19990518

Priority
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• EP 9903420 W 19990518

Abstract (en)
[origin: US6646253B1] In a gas inlet structure for an ion source, including a capillary for the admission of a sample gas, which capillary is disposed in a guide tube for discharging a sample gas into the guide tube, the guide tube has an open end disposed in the ion source. The guide tube includes a valve for the pulsed admission of a carrier gas to the guide tube. The guide tube, the valve and the capillary are supported in a sealed support housing from which the guide tube with the capillary disposed therein projects into the ion source for supplying thereto the sample gas in a pulsed manner.

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H01J 49/04

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